

Day : Thursday  
Date: 11/20/2003

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## PALM INTRANET

## Inventor Name Search Result

Your Search was:

Last Name = SHIMODA

First Name = ATSUSHI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 15
<a href="#"><u>10242362</u></a>	Not Issued	030	09/13/2002	IMAGE DETECTION METHOD AND ITS APPARATUS AND DEFECT DETECTION METHOD AND ITS APPARATUS	SHIMODA, ATSUSHI
<a href="#"><u>10218463</u></a>	Not Issued	030	08/15/2002	METHOD AND APPARATUS FOR INSPECTING PATTERN DEFECTS	SHIMODA, ATSUSHI
<a href="#"><u>10050778</u></a>	Not Issued	030	01/18/2002	APPARATUS AND METHOD FOR INSPECTING PATTERN	SHIMODA, ATSUSHI
<a href="#"><u>10012380</u></a>	6556955	150	12/12/2001	METHOD OF DETERMINING LETHALITY OF DEFECTS IN CIRCUIT PATTERN INSPECTION, METHOD OF SELECTING DEFECTS TO BE REVIEWED, AND INSPECTION SYSTEM OF CIRCUIT PATTERNS INVOLVED WITH THE METHODS	SHIMODA, ATSUSHI
<a href="#"><u>09944858</u></a>	Not Issued	071	08/31/2001	METHOD AND APPARATUS FOR INSPECTING DEFECTS OF A SPECIMEN	SHIMODA, ATSUSHI
<a href="#"><u>09783604</u></a>	Not Issued	030	02/15/2001	A METHOD AND SYSTEM FOR ANALYZING CIRCUIT PATTERN DEFECTS	SHIMODA, ATSUSHI
<a href="#"><u>09743560</u></a>	Not Issued	061	01/09/2001	METHOD FOR OBSERVING SPECIMEN AND DEVICE THEREFOR	SHIMODA, ATSUSHI
<a href="#"><u>09553944</u></a>	6456951	150	04/21/2000	METHOD AND APPARATUS FOR PROCESSING INSPECTION DATA	SHIMODA, ATSUSHI
<a href="#"><u>09421093</u></a>	6476388	150	10/19/1999	SCANNING ELECTRON MICROSCOPE, DEFECT	SHIMODA , ATSUSHI

				PORTION ANALYZING METHOD USING THE SAME AND APPARATUS AND METHOD OF AUTOMATICALLY SAMPLING IMAGE THEREOF	
<u>09225513</u>	6334097	150	01/06/1999	METHOD OF DETERMINING LETHALITY OF DEFECTS IN CIRCUIT PATTERN INSPECTION METHOD OF SELECTING DEFECTS TO BE REVIEWED AND INSPECTION SYSTEM OF CIRCUIT PATTERNS INVOLVED WITH THE METHODS	SHIMODA , ATSUSHI
<u>08960954</u>	Not Issued	161	10/30/1997	METHOD FOR THE CONTROLLED FORMATION OF VOIDS IN DOPED GLASS DIELECTRIC FILMS	SHIMODA , ATSUSHI
<u>08564922</u>	5719084	150	11/29/1995	METHOD FOR THE CONTROLLED FORMATION OF VOIDS IN DOPED GLASS DIELECTRIC FILMS	SHIMODA , ATSUSHI
<u>08179166</u>	Not Issued	166	01/10/1994	METHOD FOR THE CONTROLLED FORMATION OF VOIDS IN DOPED GLASS DIELECTRIC FILMS	SHIMODA , ATSUSHI
<u>08023650</u>	Not Issued	163	02/26/1993	METHOD FOR FORMING A THICK DOPED GLASS DIELECTRIC FILM WITHOUT VOIDS	SHIMODA , ATSUSHI
<u>08023304</u>	5278103	150	02/26/1993	METHOD FOR THE CONTROLLED FORMATION OF VOIDS IN DOPED GLASS DIELECTRIC FILMS	SHIMODA , ATSUSHI

Inventor Search Completed: No Records to Display.

**Search Another: Inventor**

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